

Report on Vacuum System

KEKB Accelerator Review
January 24, 1997

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for
KEKB Vacuum Group

Present status of preparation

LER(except Tsukuba and Injection straight)
now manufacturing, will be completed June 1997

HER(except Tsukuba and Injection straight)
now final check of drawing, will be completed March 1998

Tsukuba, Injection, Other special chamber.
contract May 1997, most part will be completed March 1998

Table 1. Parameters of KEKB Vacuum

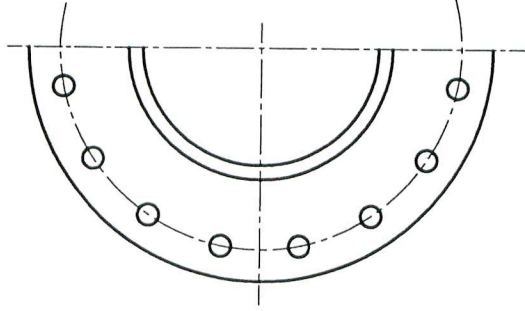
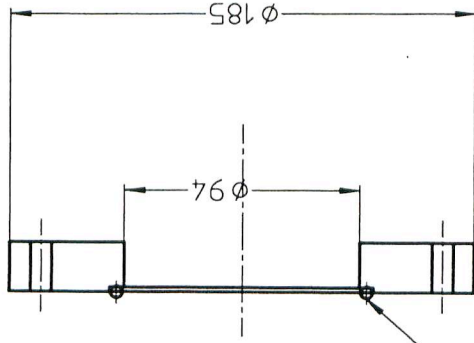
	LER	HER	
Beam energy	3.5	8.0	GeV
Beam current	2.6	1.1	A
Circumference	3016	←	m
Bunch length	4	←	mm
Bending radius	16.31	104.46	m
Total Power of SR	2117 (arc)	3817	kW
Critical Energy of SR	5.84	10.9	keV
Total photon flux of SR	7.35×10 ²¹	7.11×10 ²¹	photons s ⁻¹
Local maximum of the linear power density	14.8 (bend)	5.8 (bend)	kW m ⁻¹
	~13 (wiggler front)		
	~10 (wiggler)		
	OFC (6)	←	(mm)
Duct material (thickness)			
Radiation dose on duct surface	<10 ⁵	<10 ⁷	rad year ⁻¹
Maximum temperature	120 (bend)	not estimated	°C
Maximum strain	-0.15 (bend)	not estimated	%
Surface exposed to SR	wall of beam duct	←	
Average linear photon density	3.3×10 ¹⁸	3.2×10 ¹⁸	photons s ⁻¹ m ⁻¹
Average pressure with beam	~10 ⁻⁹	←	Torr
Average base pressure	~10 ⁻¹⁰	←	Torr
Photo desorption coefficient	10 ⁻⁶	←	molec. photon ⁻¹
Static outgassing rate	<10 ⁻¹¹	←	Torr l s ⁻¹ cm ⁻²
Linear pumping speed	100 (target)	←	l s ⁻¹ m ⁻¹
Cross section of duct	circle	←	
Conductance of beam duct (1m)	102	←	
Arrange of pump	array of port	←	
Main pump	NEG cartridge	←	
		racetrack	
		52.3	
		integrated+port	
		NEG strip	

LER=Low Energy Ring, HER=High Energy Ring, SR=Synchrotron Radiation, NEG=Non Evaporable Getter (SAES)

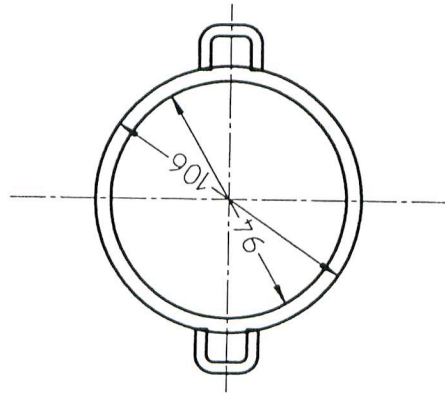
Duct cross section and Flange connection

The cross section of a duct is symmetric in ST, Q, and SX.

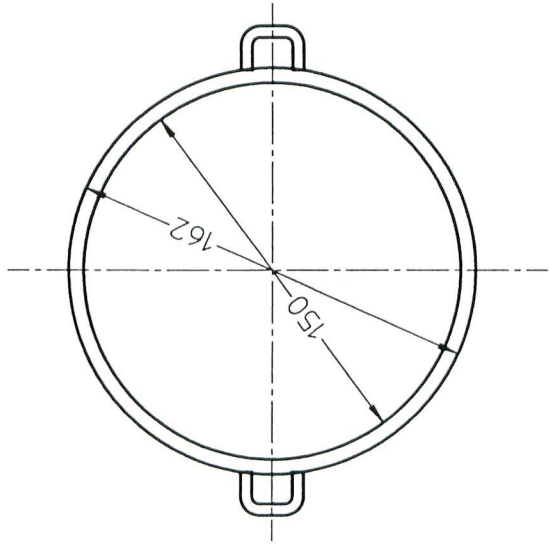
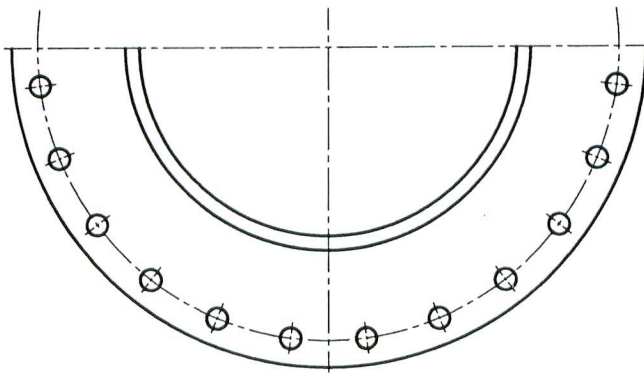
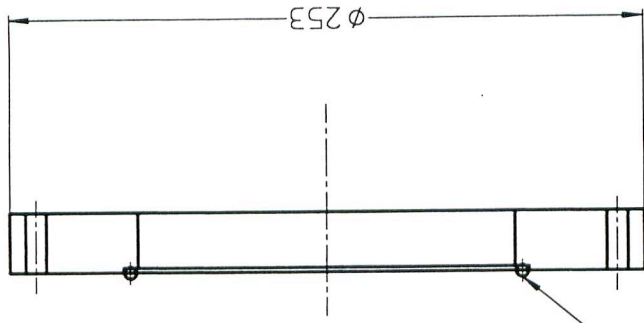
Helicoflex is used for vacuum seal and rf contact.



Helicoflex
vacuum seal/rf contact

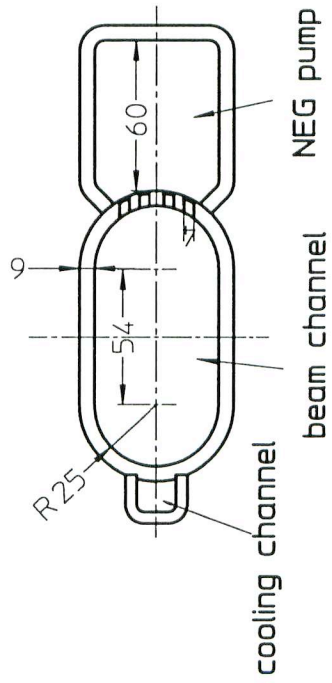
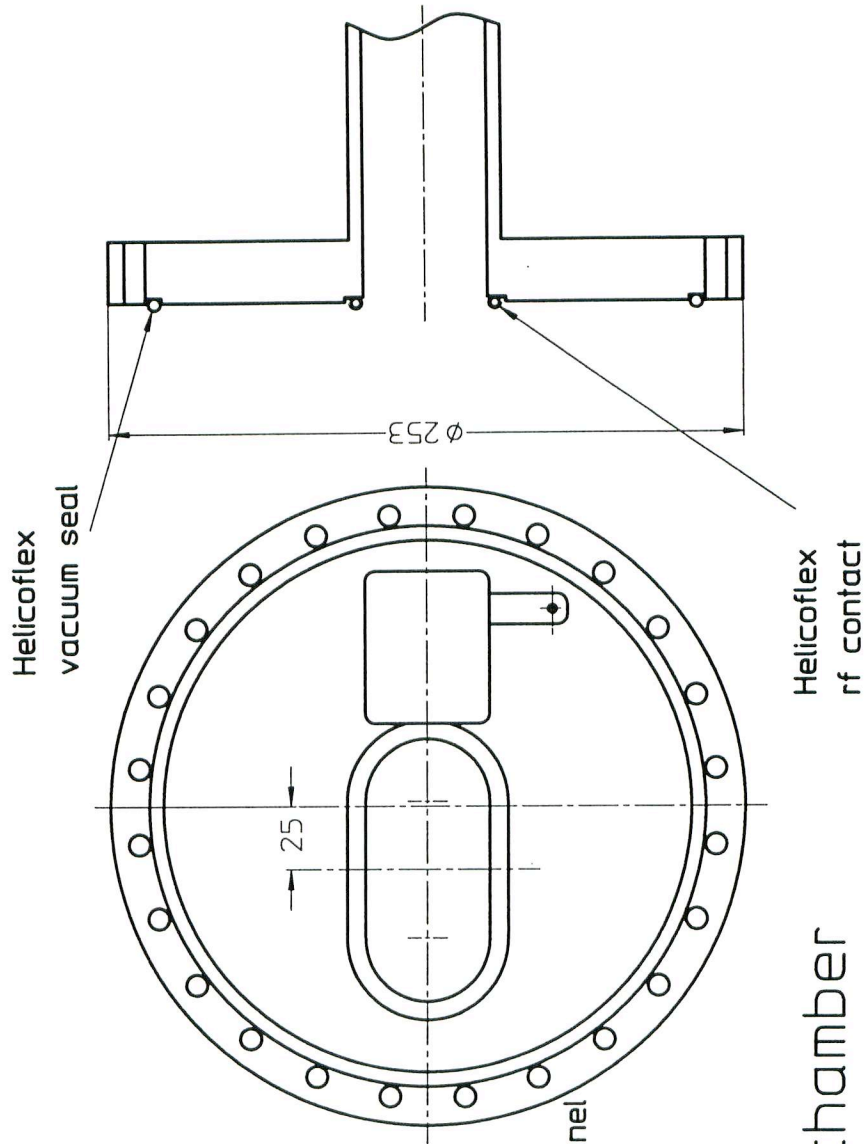


LER chamber

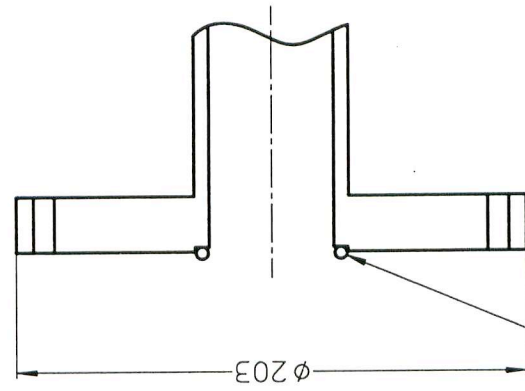


LER/HER RF-Q-chamber

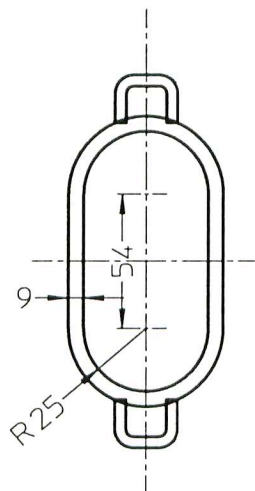
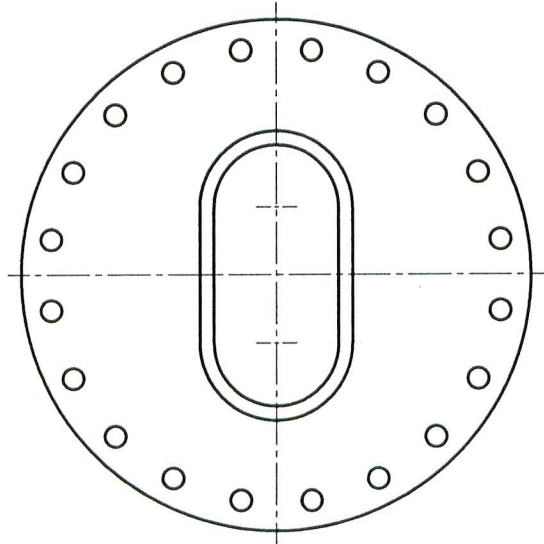
Helicoflex
vacuum seal/rf contact



HER B-chamber



Helicoflex
vacuum seal/rf contact



HER Q-chamber

Setting Q-chambers

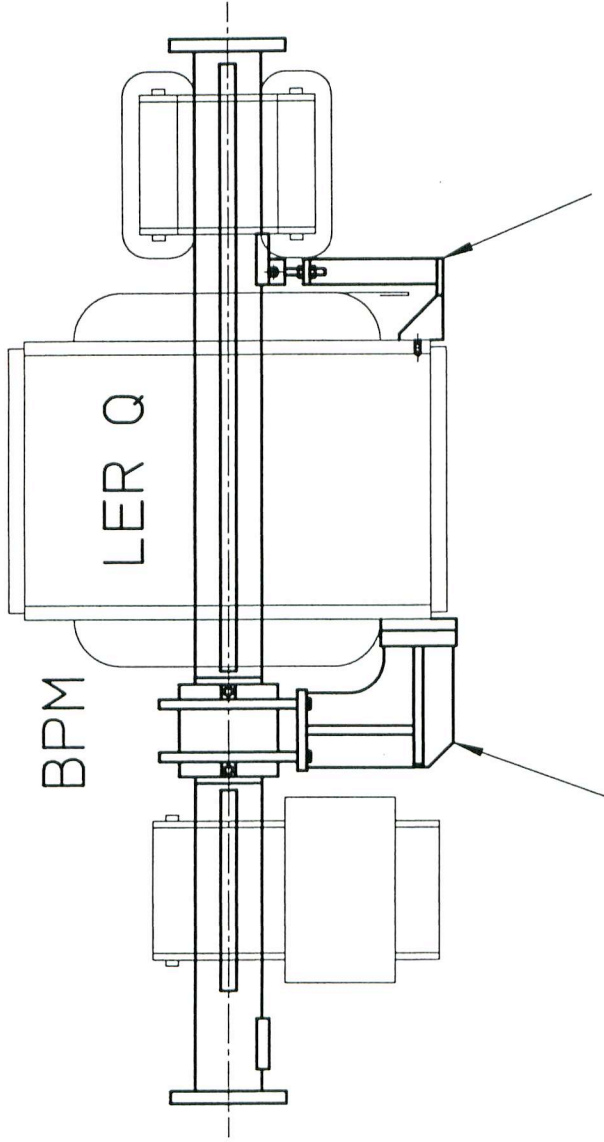
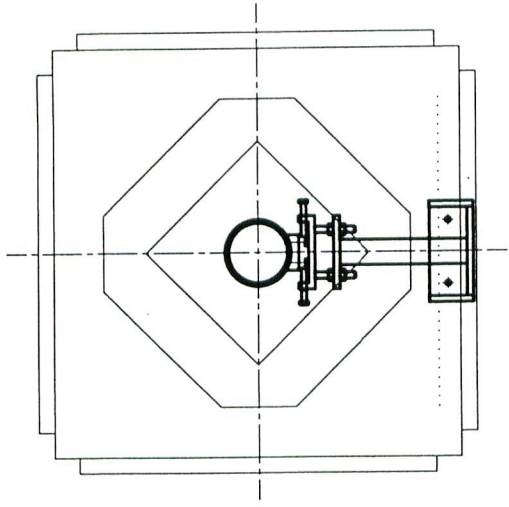
The position of Q-chamber is mainly determined by a BPM support.

The setting error will be less than ± 1 mm.

The effect of centering error in beam based alignment.

M. Kikuchi, K. Egawa, H. Hukuma, and M. Tejima, 'Beam based alignment of sextupoles with the modulation method', Proc. of PAC, Dallas, USA, 603(1995).

For a ± 1 mm horizontal shift of a vacuum chamber, the offset of a measured value is less than $\pm 1.4\%$ that of asymmetry. Or at 0.6Hz modulation, a residual offset is ± 6 micron. Can be corrected by changing frequency.



Chamber support

BPM support

UNITS	
Length	: MM
Flux density	: TESL
Field strength	: AM
Potential	: WBM
Conductivity	: SM
Source density	: AM2
Power	: WATT
Force	: NEWT
Energy	: JOUL
Mass	: KG

PROBLEM DATA
 Linear elements
 XY symmetry
 Vector potential
 Magnetic field
 No mesh
 75 regions

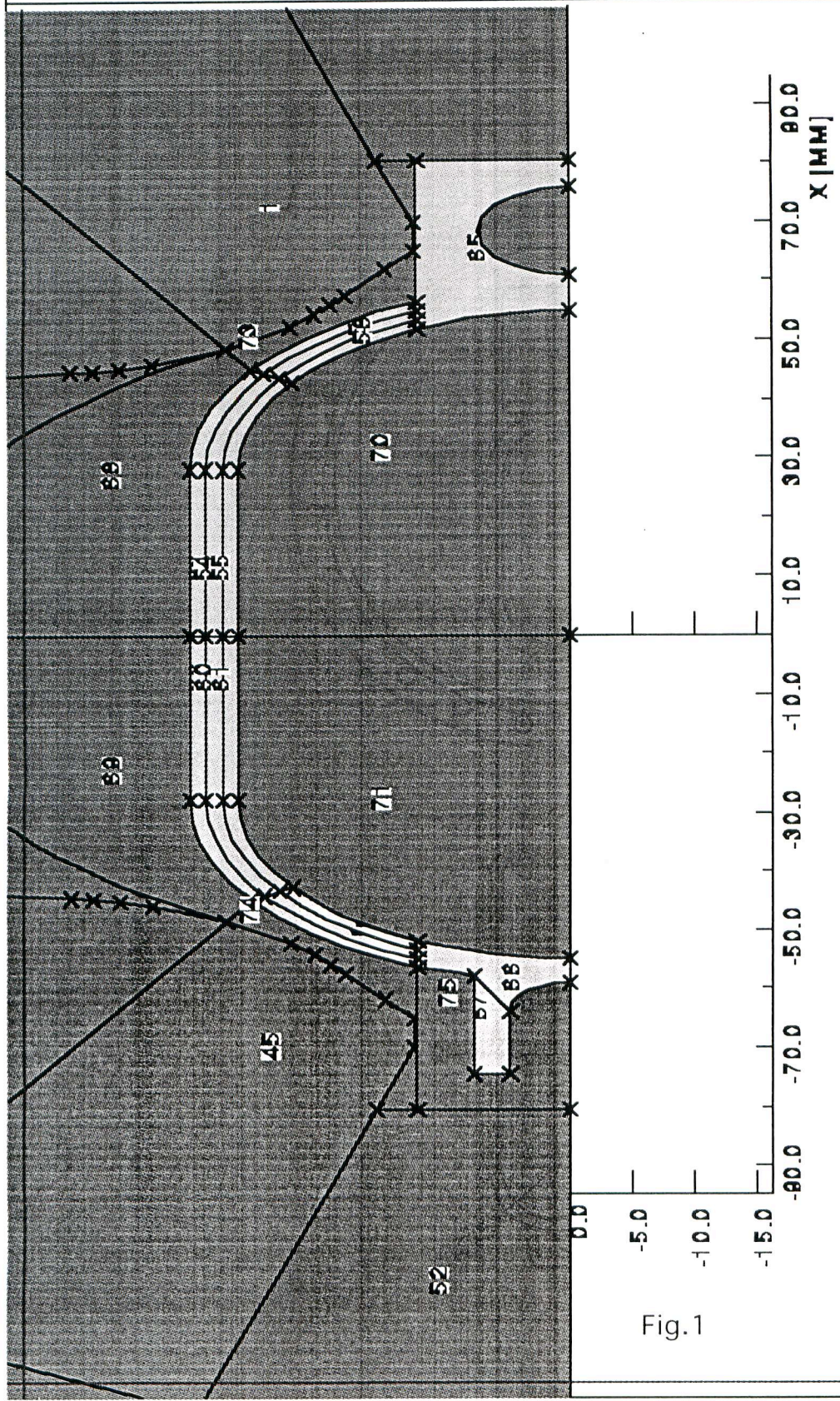
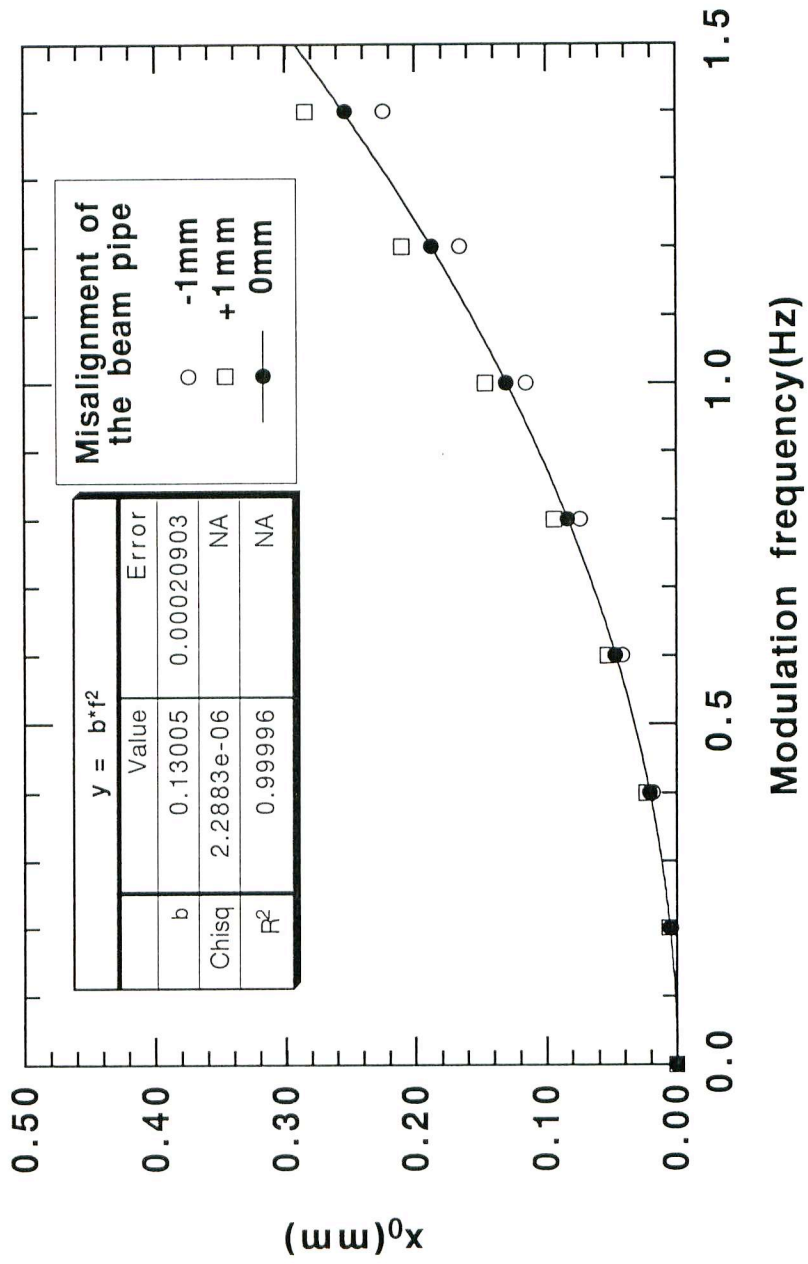


Fig.1



Pumping concept

Roughing port: every 40m, sputter ion pump: every 10m, and

LER: NEG cartridge port: every 1m

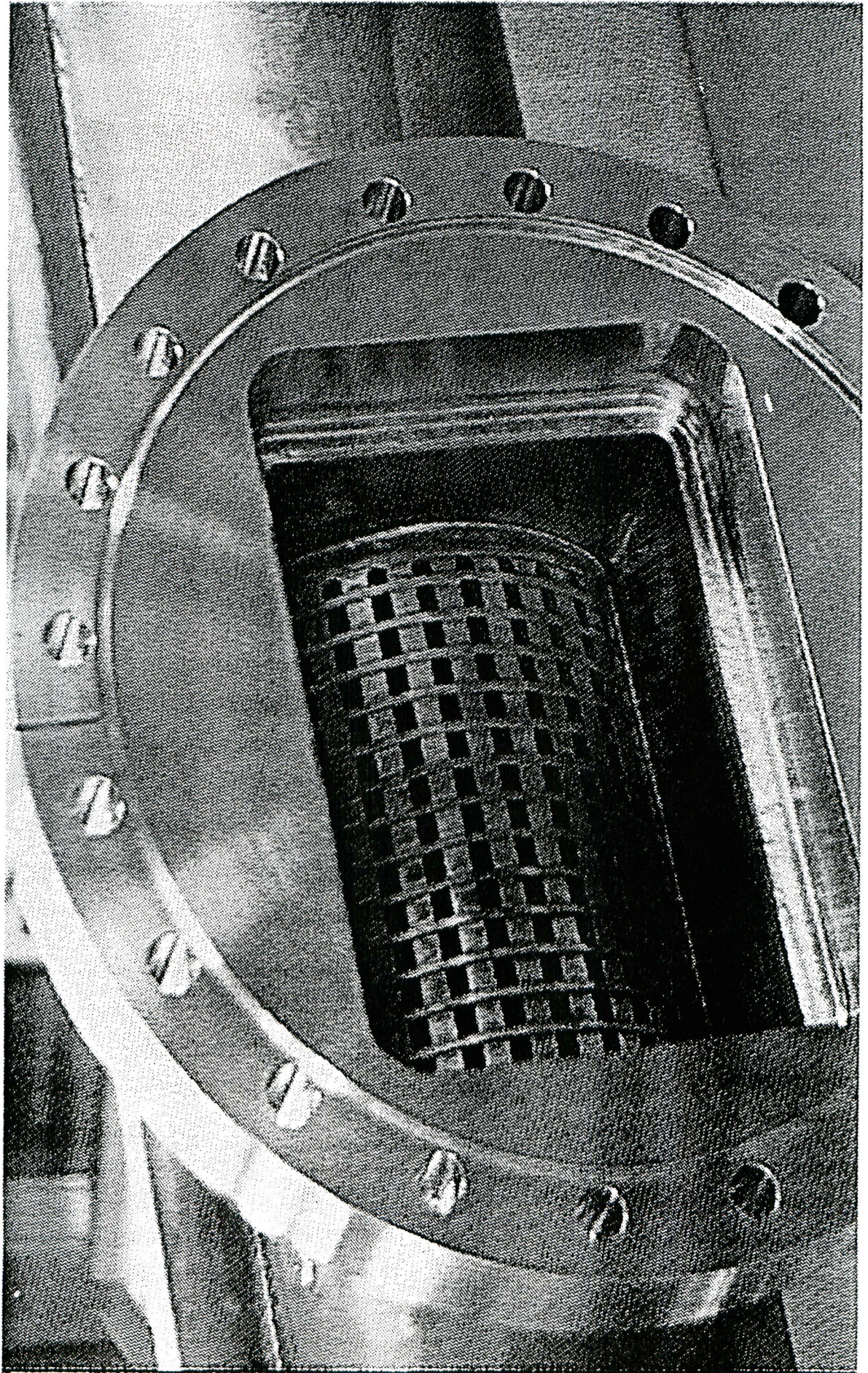
HER: NEG strip in a bend +NEG cartridge port: every 1m.

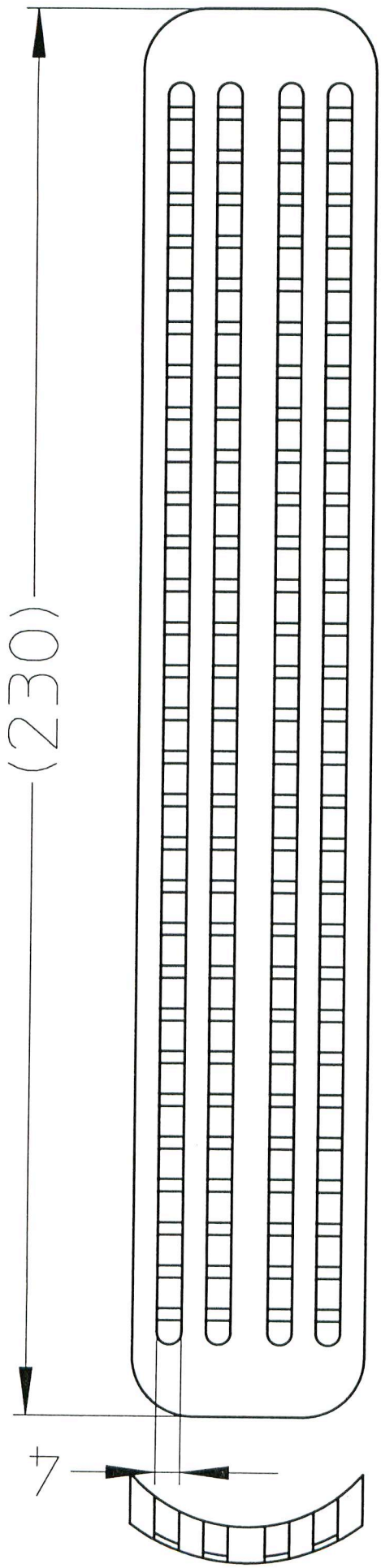
Use grid, not slot.

Calculated pumping speed for an actual layout is about $60 \text{ ls}^{-1}\text{m}^{-1}$.
(Design aim is $100 \text{ ls}^{-1}\text{m}^{-1}$)

NEG's are conditioned after 0.1 Torr lm^{-1} absorption.

(The first conditioning is after 0.25 Ah for LER, 0.5 Ah for HER)



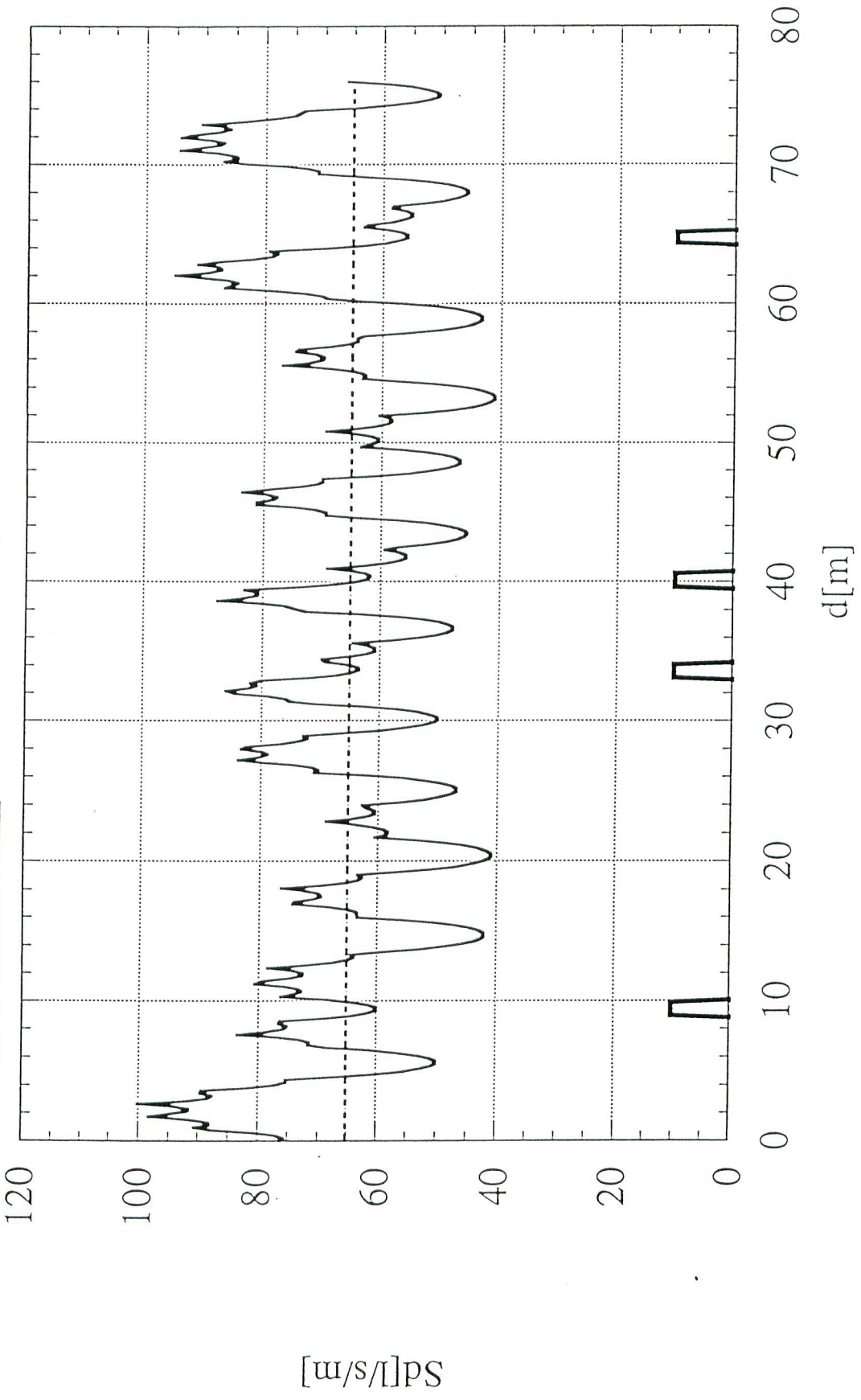


x20 for HER B-chamber

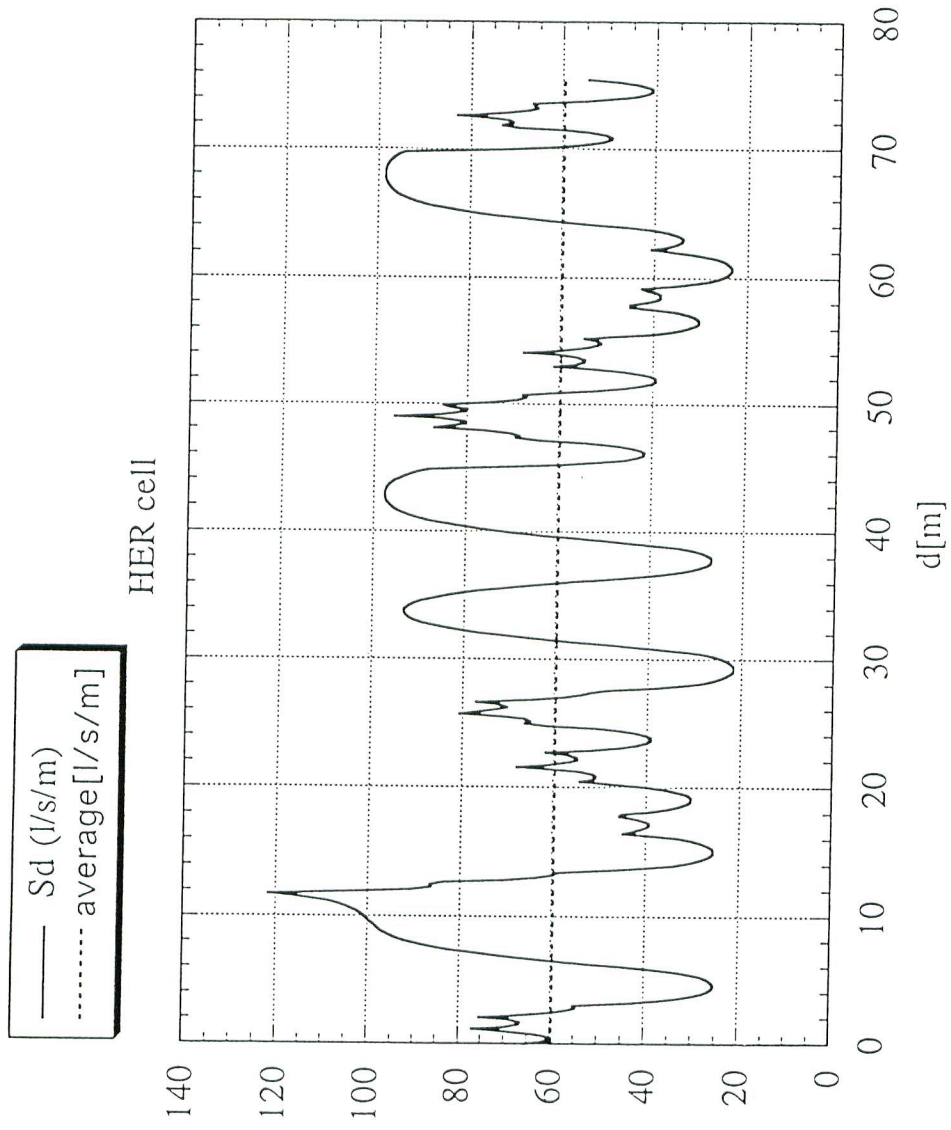
LER Cell



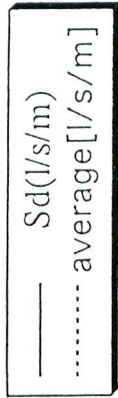
cell_eps



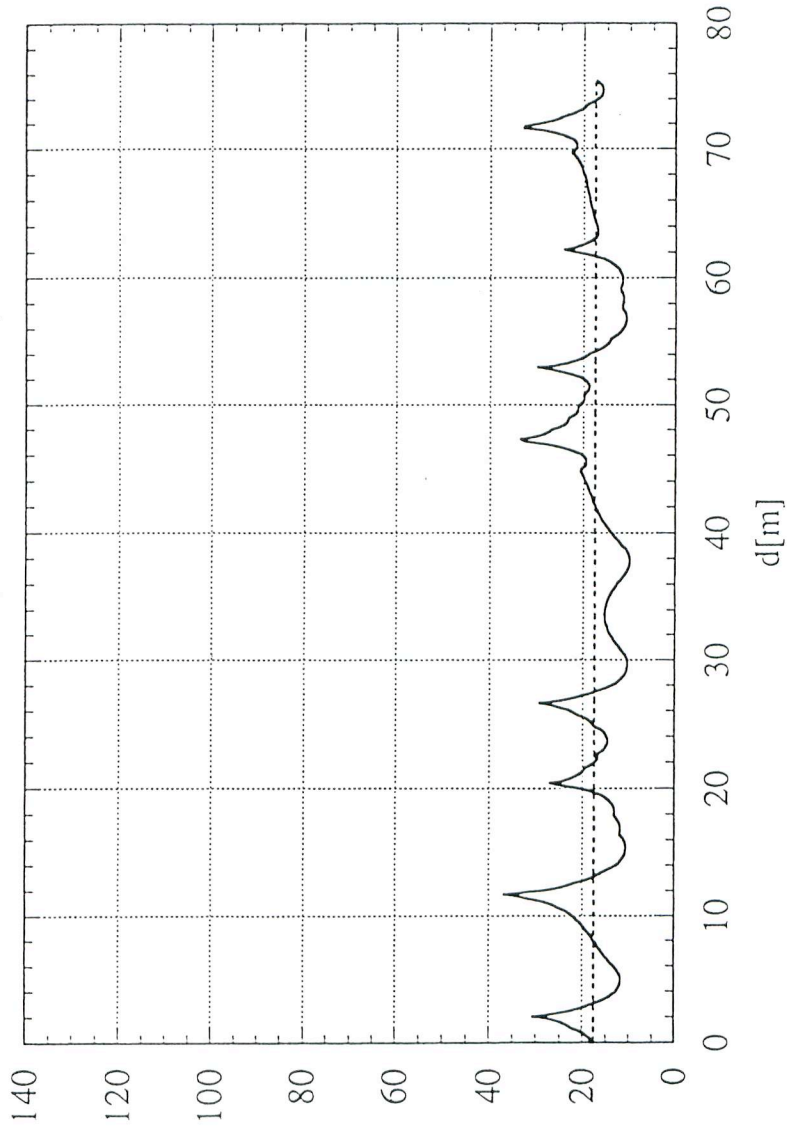
distributed pumping speed (l/s/m)



distributed pumping speed (l/s/m)



HER cell (after 0.1 Torr l/m)



Cleaning

Two problems in fabrication of LER chambers (in US, Due to insufficient communication).

1. Citranox cleaning for an extruded surface.

Though this is useful for a once cleaned surface. Effectiveness for an extruded surface is doubtful because Citranox removes only little amount of a surface, about $\sim 10 \text{ \AA}$ which is $1/1000$ of the specification ($1 \mu\text{m}$)

2. Inside welding of flanges.

It is adopted to prevent virtual leak due to voids in the bottom of a welded zone. But work to remove sputtered and evaporated copper have a risk of scratches on a sealing surface.

First step measure for the rest of LER chambers.

1. Acid cleaning (in Japan) for a duct pipe.
2. Use of masks

In parallel, PID experiment will be done at NSLS (collaboration with C.L.Foerster) to check,

- a) the effect of Citranox cleaning on an extruded surface,
- b) that a photon desorption coefficient of 10^{-6} is attainable by an acid cleaned chamber.

Second step for HER chambers

1. Use Citranox only for parts (grid, pump port etc).
2. Outside welding

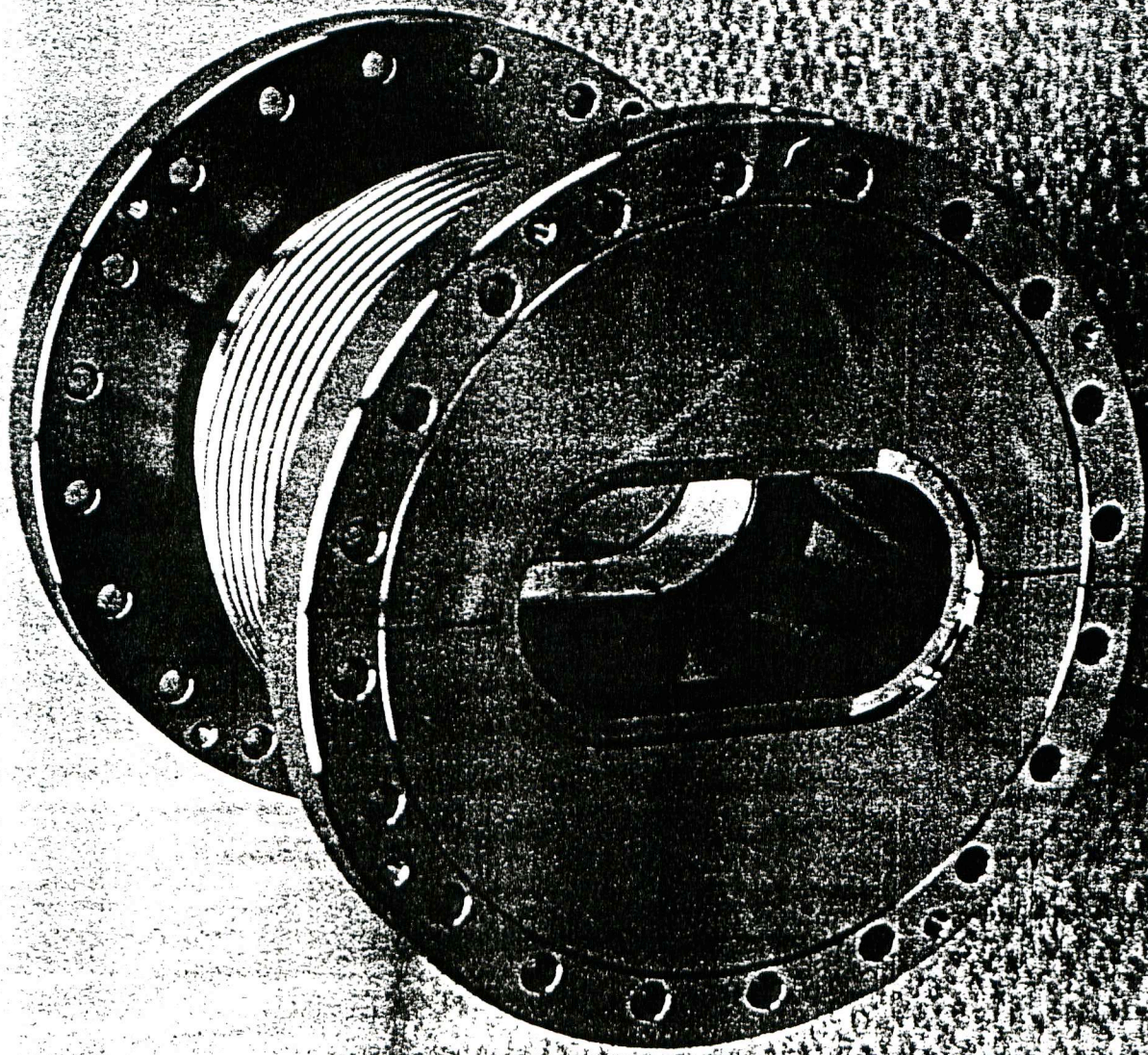
Bellows

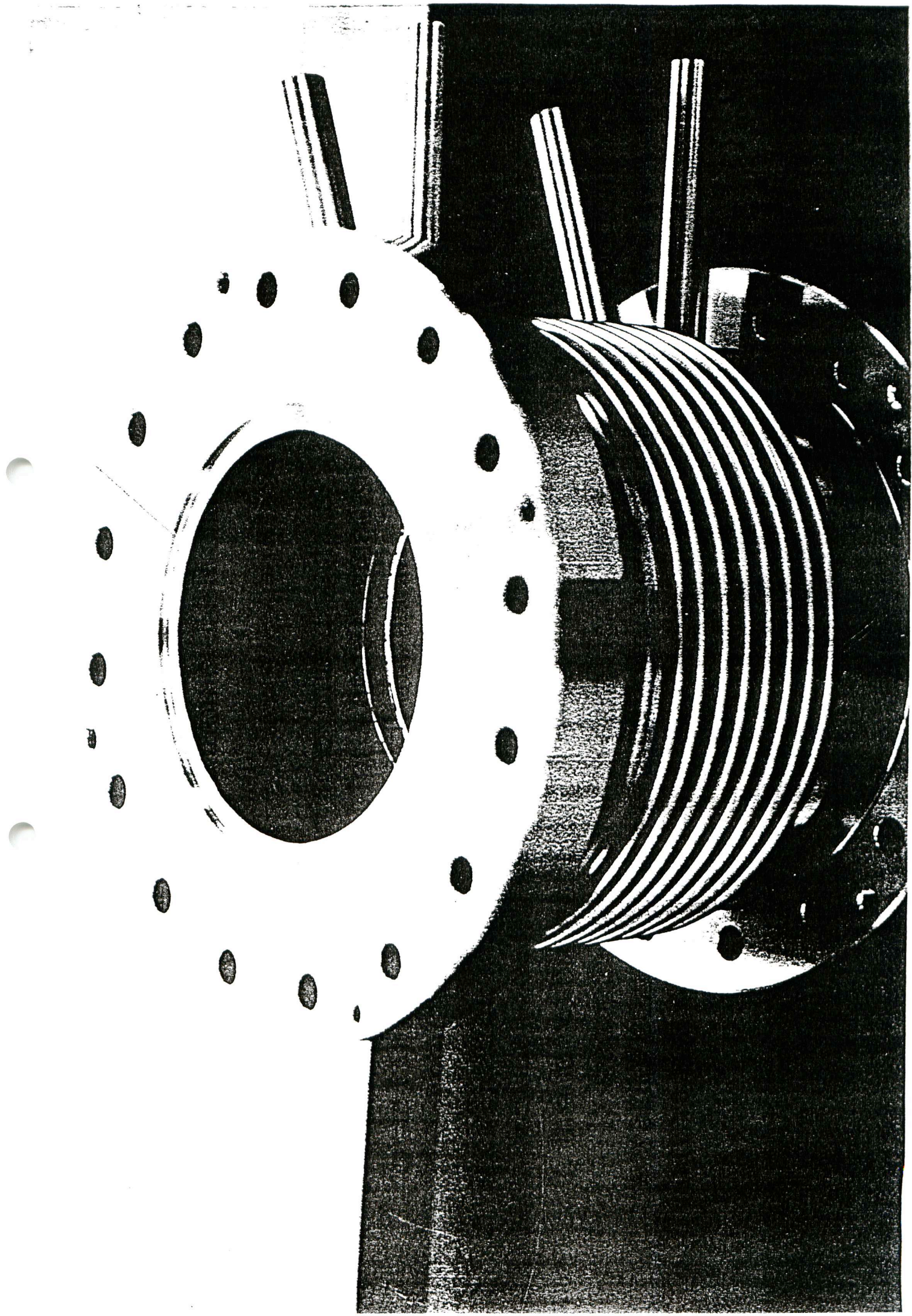
Y. Suetsugu, K. Ohshima, and K. Kanazawa
'Design studies on a vacuum bellows assembly with radio
frequency shield for the KEK B factory', Rev. Sci. Instrum. **67**
2796(1996).

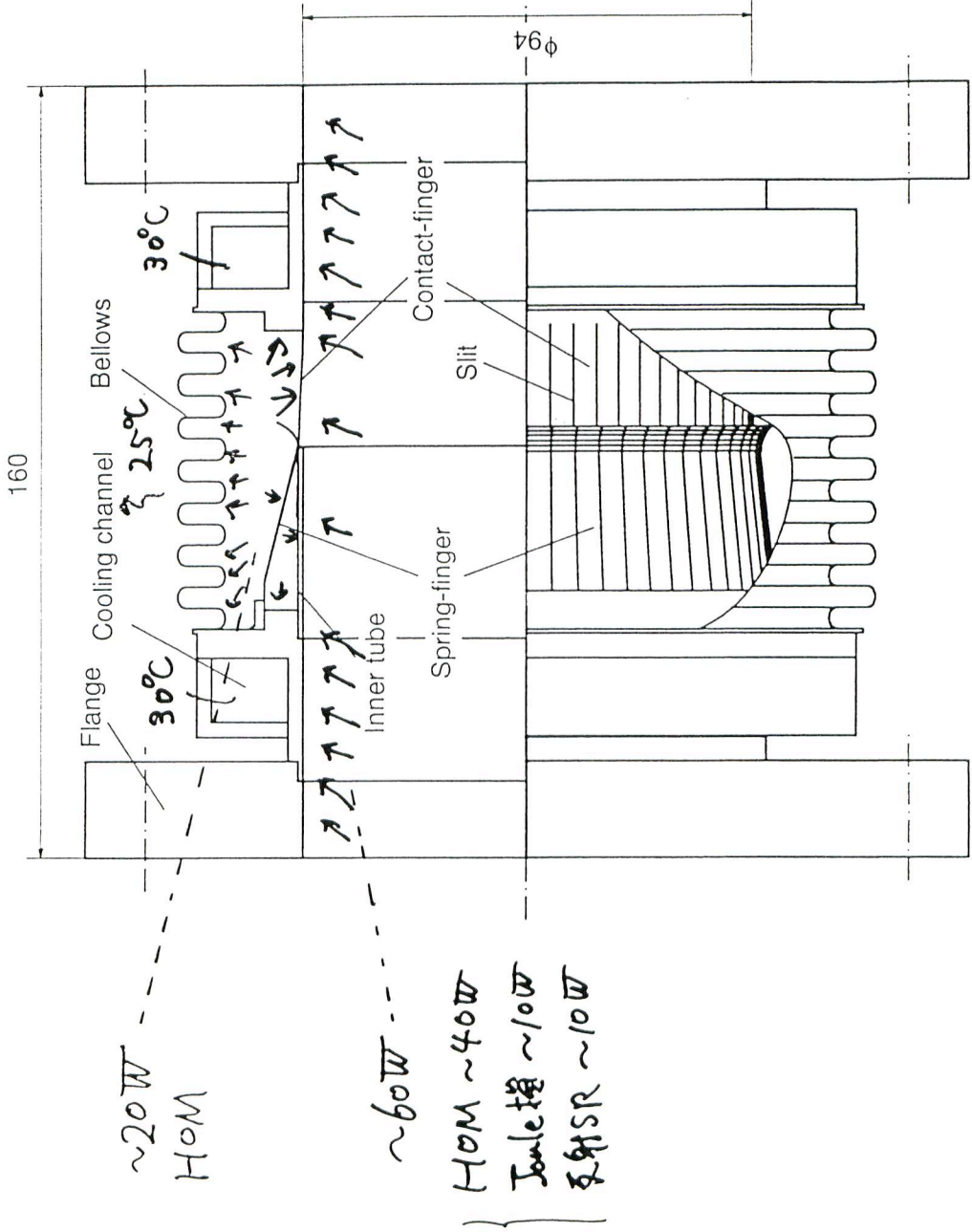
High power test for the rf contact.

Measurement of the coupling coefficient β of the rf shield for a basic
TM mode.

Max temperature in the bellows unit is about 60°C for a probable
case that HOM leakage is 20W, Joule loss of wall current is 10W
and heat from scattered SR is 10W.







Structure of bellows assembly for KEKB

ANSYS 5.1
JUL 29 1996
13:07:35

NODAL SOLUTION

STEP=1

SUB =1

TIME=1

TEMP

TEPC=1.039

SMN =30.056

SMX =63.492

30.056

33.771

37.486

41.201

44.916

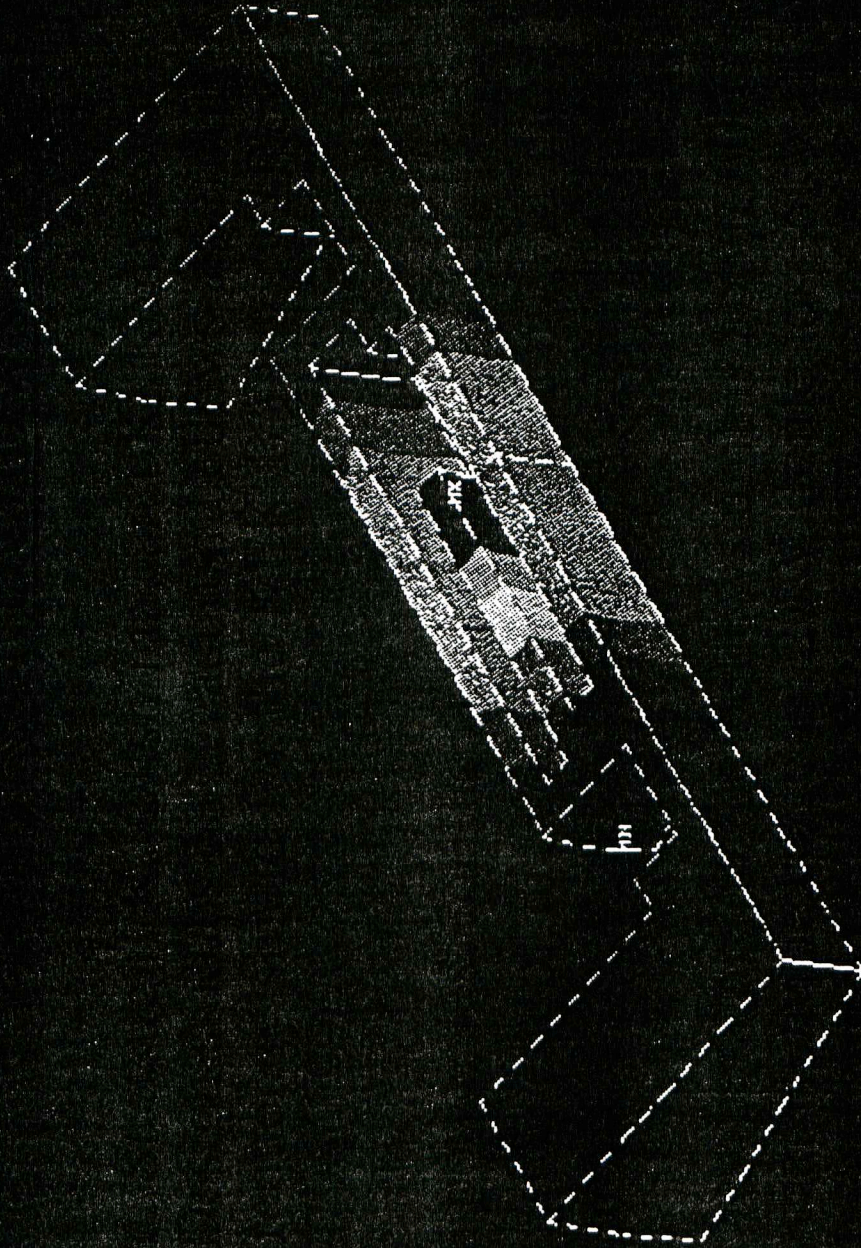
48.631

52.346

56.061

59.776

63.492



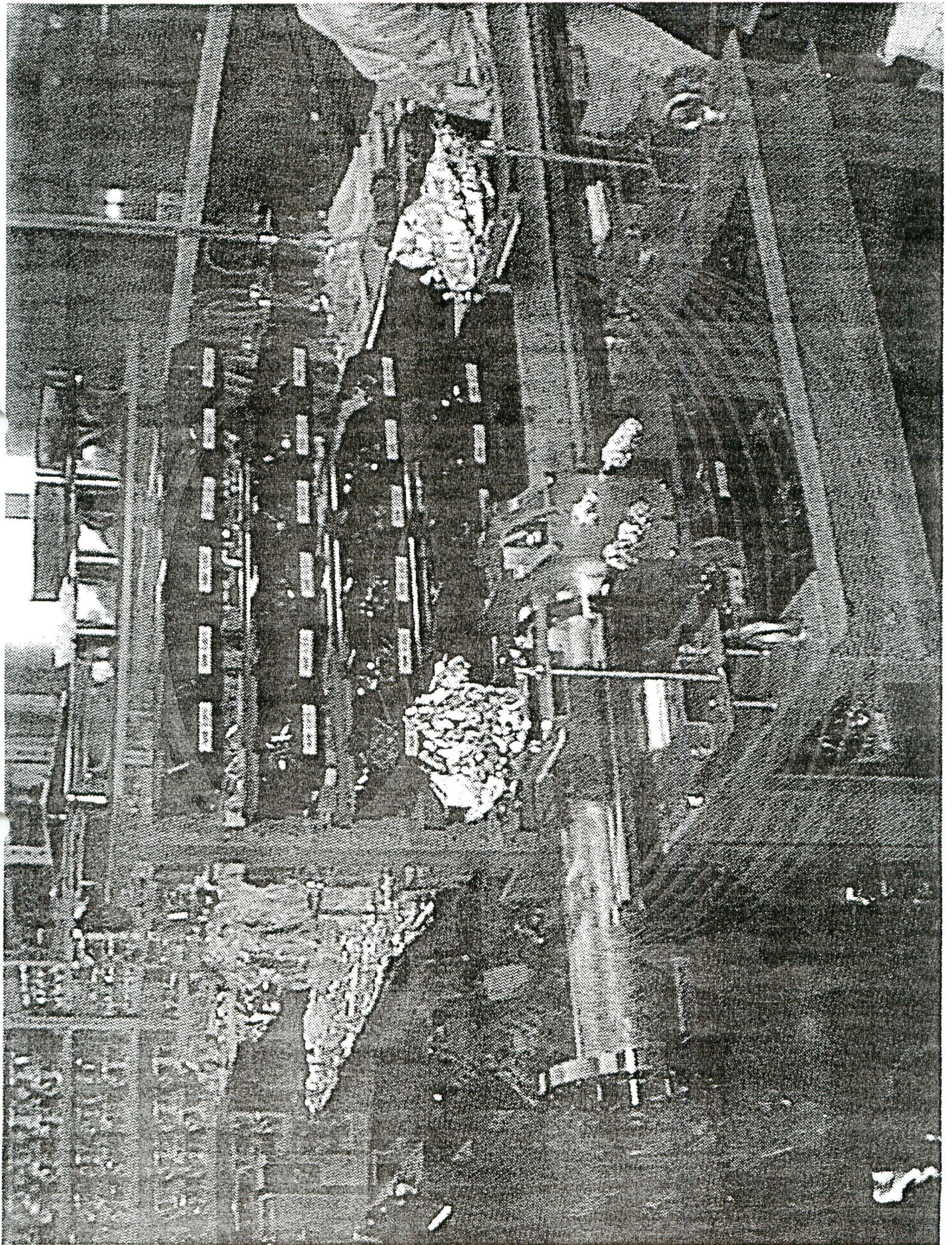
Receiving work

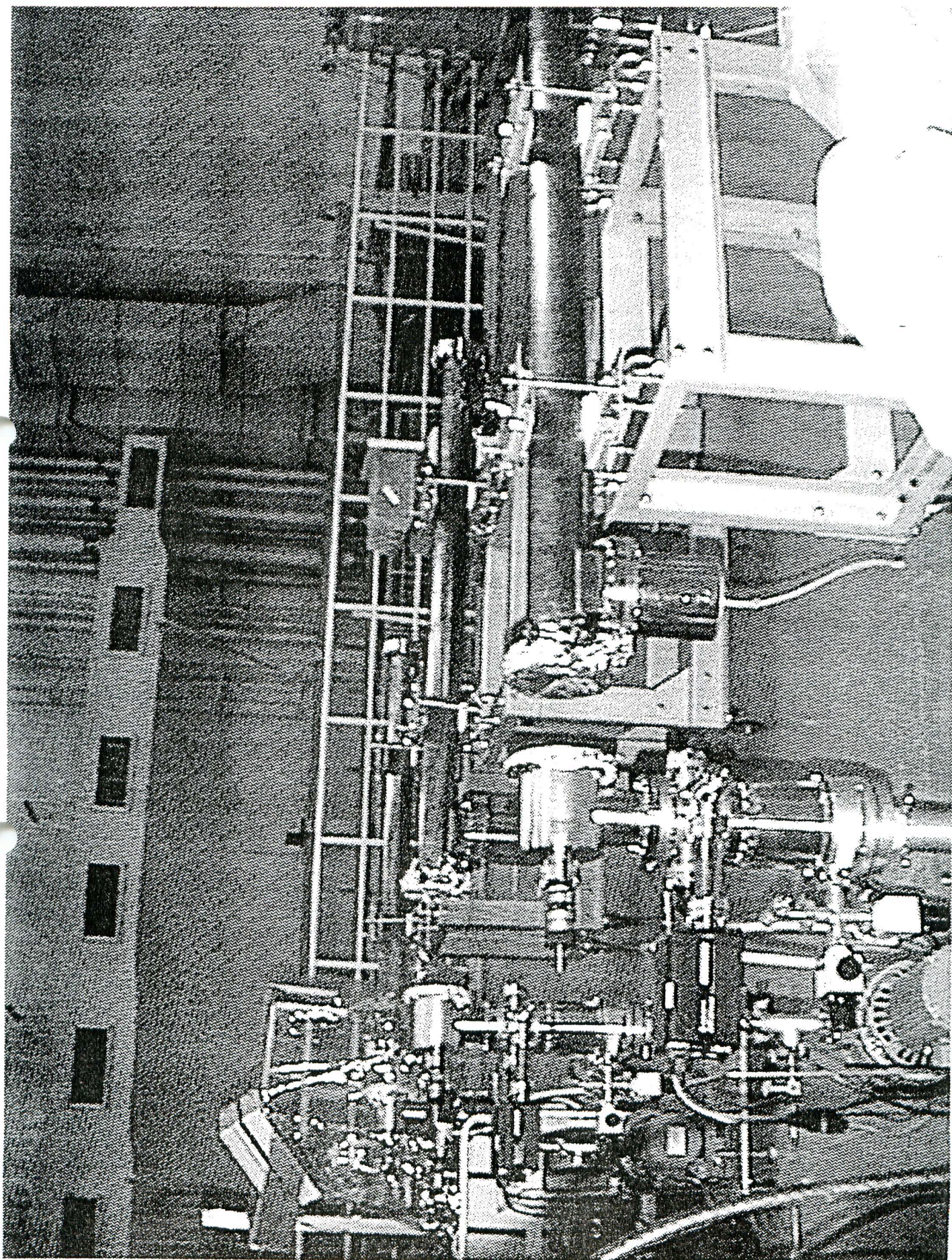
9/30/96-1/21/97

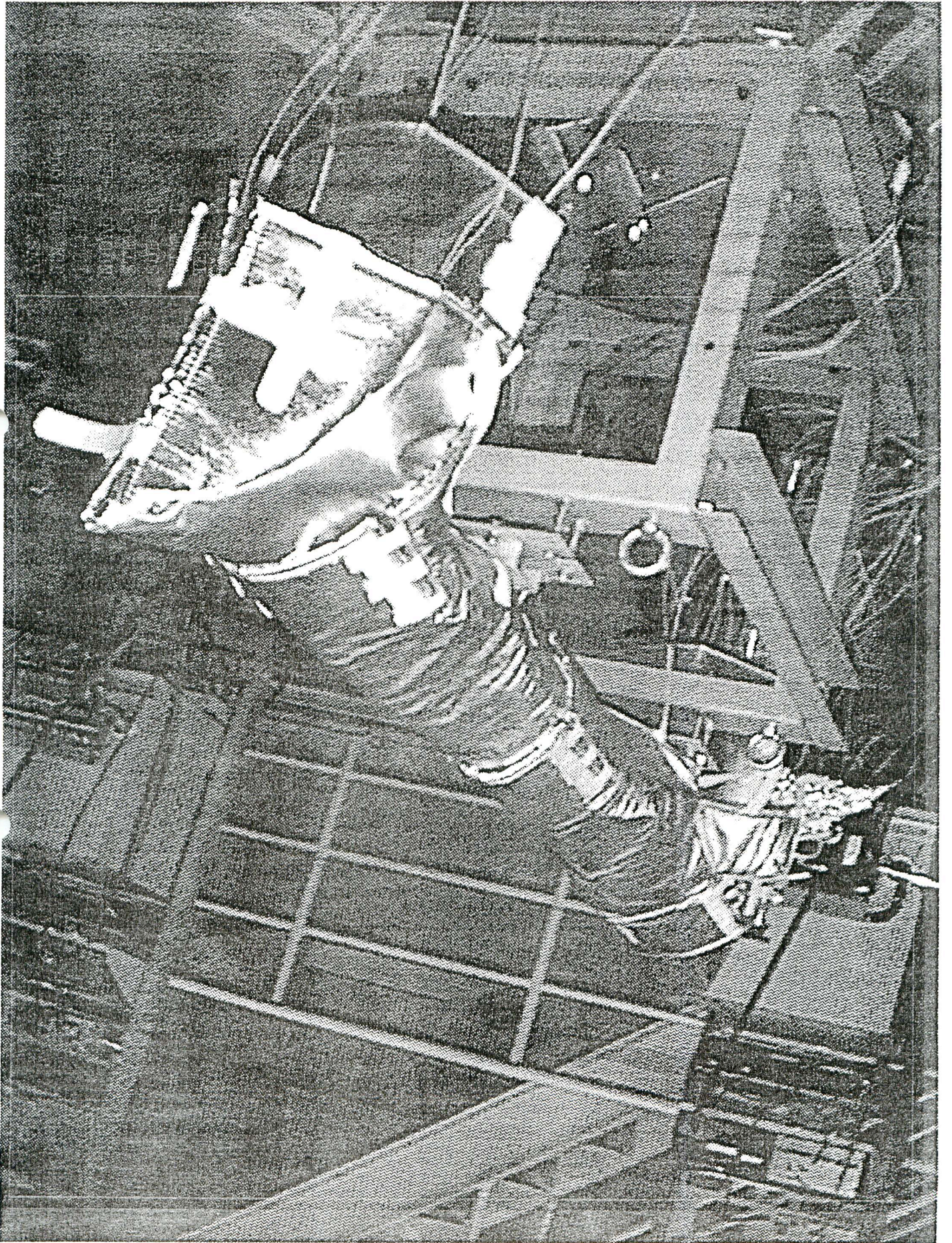
LER S-chamber; received: 38
baked and waiting N₂ purge: 5
N₂ purged: 5
LER Q-chamber; received: 30
baked and waiting N₂ purge: 6
(Plan: total received: 80)

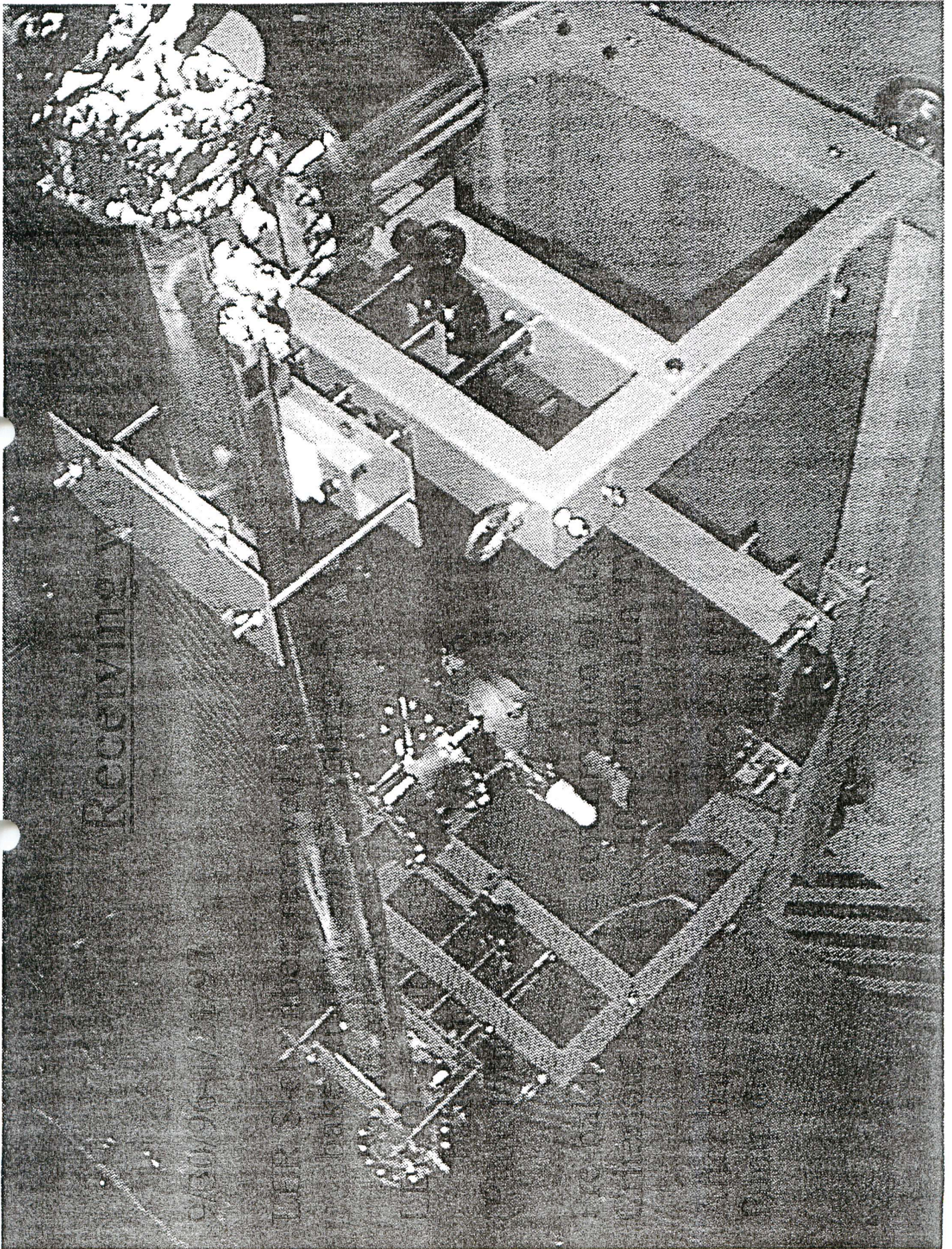
Pre-baking and the confirmation of desorption rate are done at KEK.
Criterion: Few times 10⁻¹⁰ Torr at a TMP head.

After bake-out chambers are N₂ purged and stored in the tunnel.
Pump down test for a stored duct is planned









Receiving W

0/30/06-17/21/07

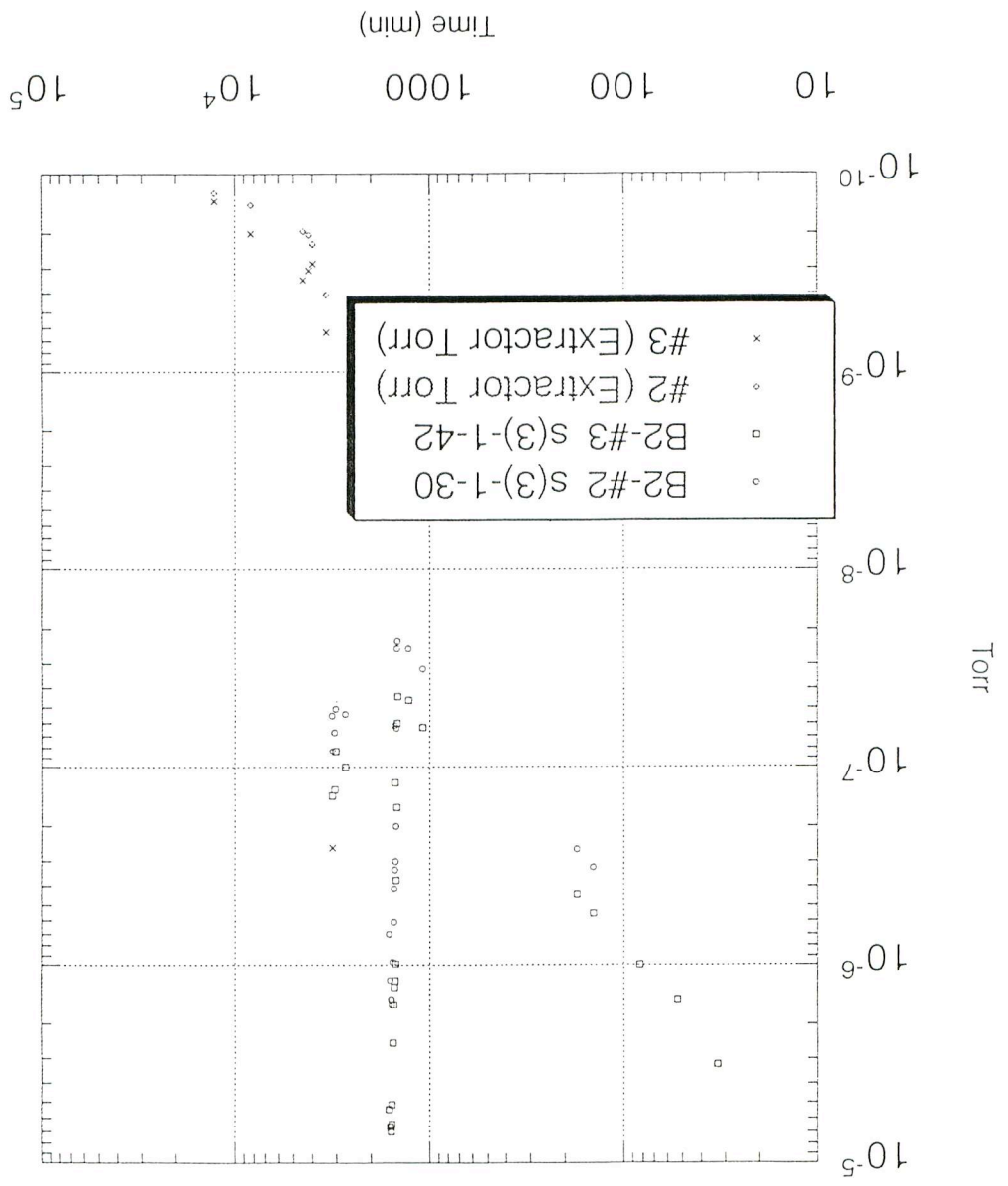
11/1/06-17/21/07

11/1/06-17/21/07

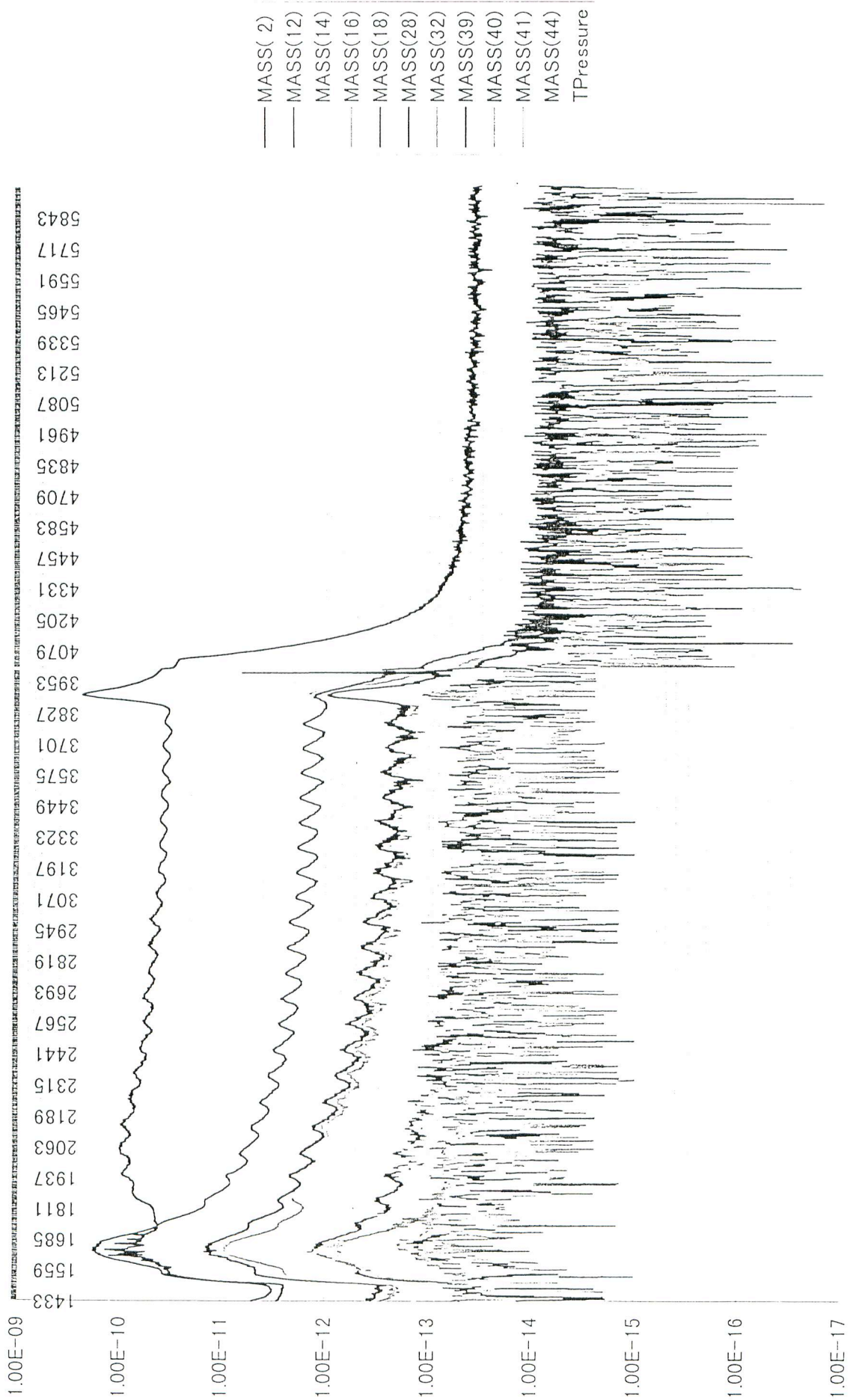
11/1/06-17/21/07

11/1/06-17/21/07

970107 s3pumping



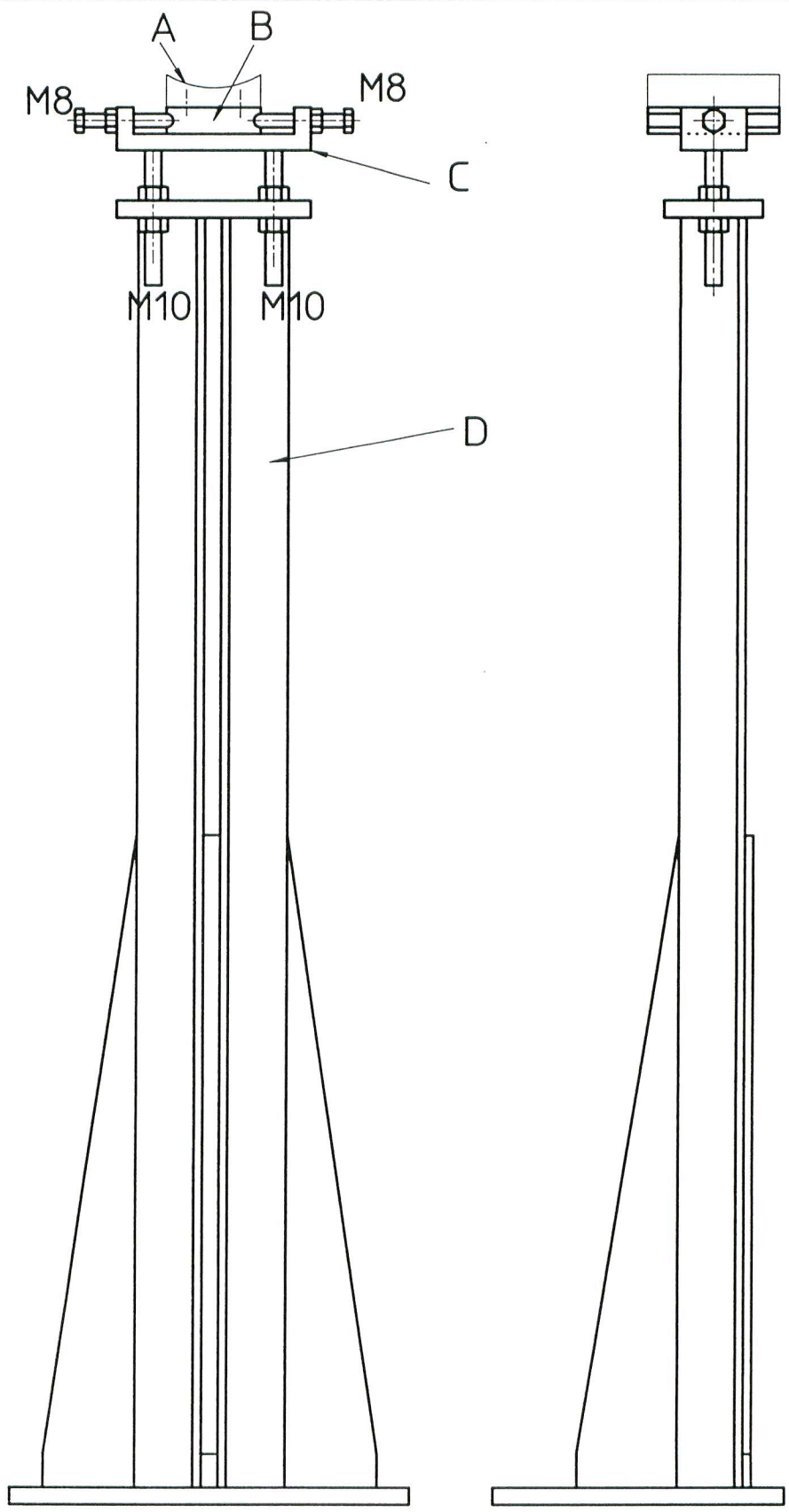
0107-2BK グラフ 1

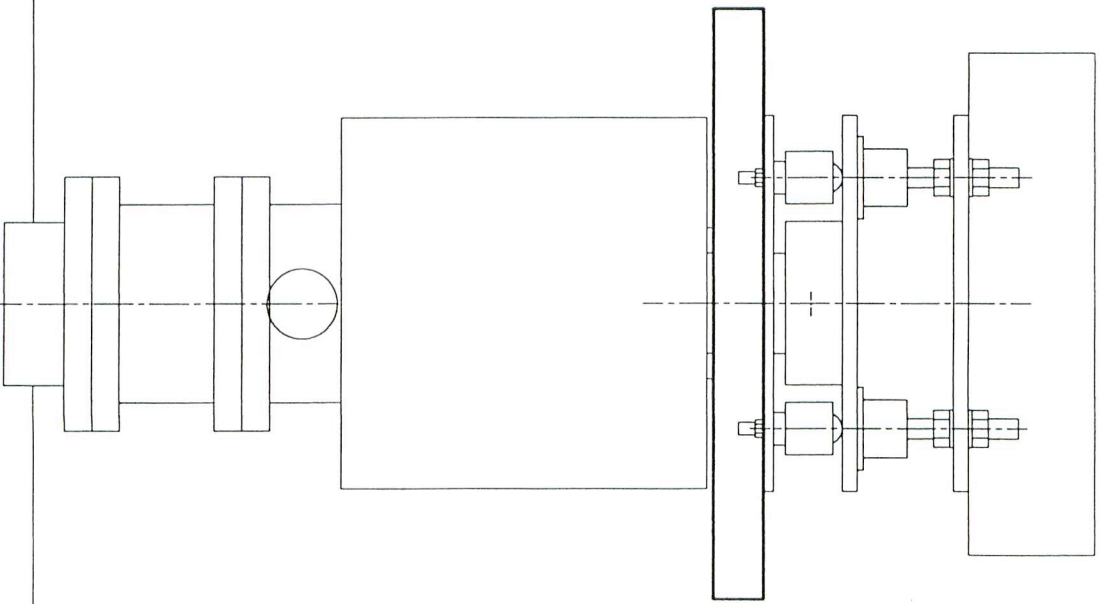
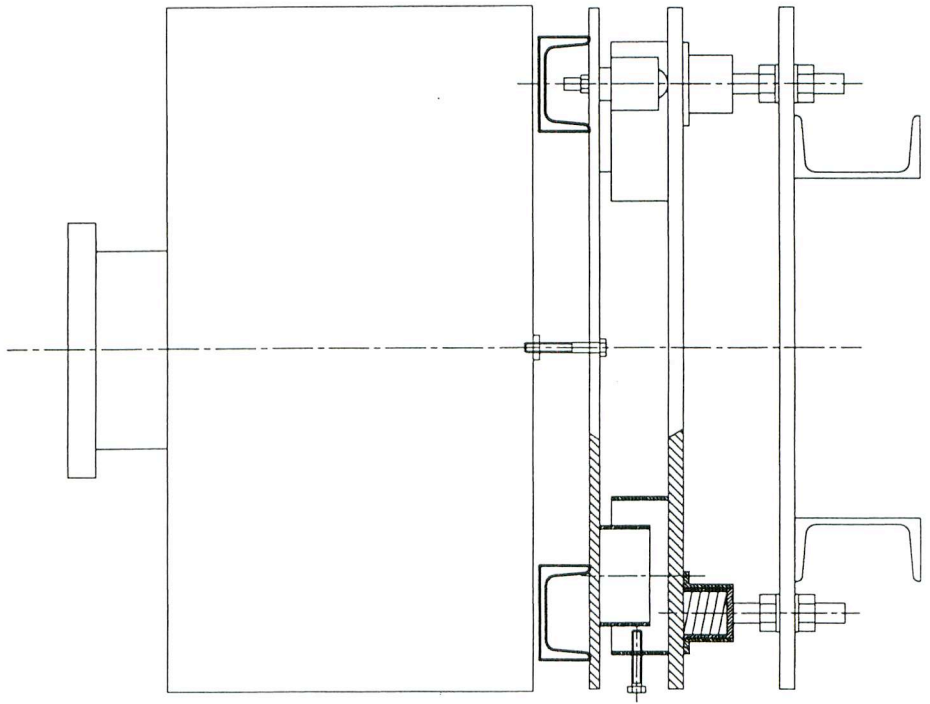


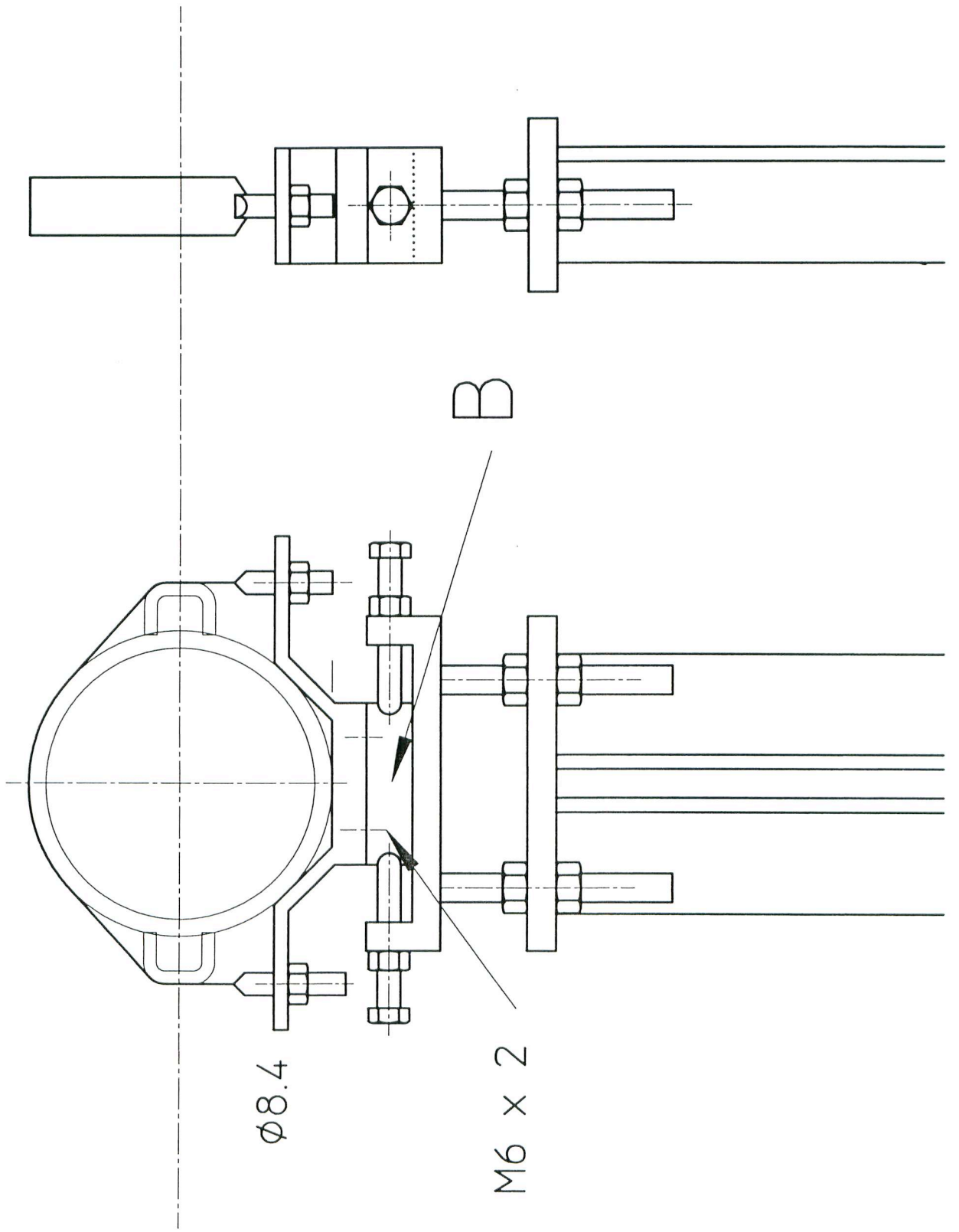
Preparation for installation

A longitudinal slide support, a fixed support, and an ion pump support, for LER S-chambers and B-chambers, and a support for LER Q-chambers are designed and contracted.

Support at a bending magnet for B-chamber, Wiggler chamber must be optimized







Heat and material

Slow fatigue test at elevated temperature is performed.
(Y. Nagai, Hitachi Cable)

A fatigue test is done for Class 1 OFC (both 1/2H and annealed)
at 100, 150, 200°C, up to 10^4 cycles.

0~0.5% strain,
one cycle = 90 sec.

Result : no sign of fatigue.

Vacuum Monitoring

Pressure:
every 10m by CCG.

Temperature:

All bellows.
All GV's.
Some NEG port.
Cooling water at high heat load.

Vacuum check with Vacuum switch and CCG.